

ABSTRACT

Method of Forming a Protective Film and a Magnetic Recording Medium Having a Protective Film Formed by the Method

5

The method of the invention deposits a protective film of a slide-resistant member by means of a plasma CVD method using a raw material of hydrocarbon gas, wherein a bias voltage higher than -500 V is applied to the slide-resistant member in an initial stage of depositing the protective film,
10 and a bias voltage of -500 V or lower is applied in a final stage of deposition.

A proportion of time duration of the final stage is preferably at most 25 % of the total time for depositing the protective film.

A magnetic recording medium of the invention comprises a magnetic recording layer and a protective film that is formed by the method defined
15 above.

Selected drawing is Fig. 1.